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Patent

JUN 01 2006

Customer No.: 31561

Docket No.: 10573-US-PA

Application No.: 10/604,793

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Applicant : Rui-Hui Wen

Application No. : 10/604,793

Filed : 2003/8/18

For : ION SAMPLING SYSTEM FOR WAFER AND SAMPLING  
METHOD THEREOF

Art Unit : 1746

Examiner : KORNAKOV, MICHAEL

TRANSMITTAL LETTER

002-1-571-273-8300

(Via fax : 1+7 pages)

Assistant Commissioner for Patents  
Alexandria, VA 22314

Dear Sir,

In response to the Office Action dated May 18, 2006(Paper No.: 20060516), please  
find the Response to Office Action, in 7 pages.

I believe that no fee is incurred. However, the Commissioner is authorized to charge  
any fees required in connection with the filing of this paper to account No. 50-2620  
(Order No.: 10573-US-PA).

Thank you for your assistance in the subject matter. If you have any questions,  
please feel free to contact me.

Respectfully Submitted,  
JIANQ CHYUN Intellectual Property Office

Date : June 1, 2006

By : Belinda Lee  
Belinda Lee  
Registration No.: 46,863

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**AMENDMENTS**

Please amend the application as indicated hereafter.

**To the Title:**

Please amend the title as follows,

**"ION SAMPLING SYSTEM FOR WAFER ~~AND SAMPLING METHOD THEREOF~~"**